

**ASSEMBLY COMPRISING A PLURALITY OF MASK CONTAINERS,
MANUFACTURING SYSTEM FOR MANUFACTURING SEMICONDUCTOR
DEVICES, AND METHOD**

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Abstract of the Disclosure

10 The present invention relates to a system for the
manufacture of semiconductor devices by lithography, and
in particular to an assembly of mask containers for use in
such a system. The system comprises: a plurality of mask
containers adapted to engage with one another such that
two or more containers can be carried together as a stack;
a plurality of lithography bays; a transport rail system
for carrying the containers between different lithography
15 bays. Each lithography bay has a transmitter/receiver
unit for communicating lithography data with a tracking
device located in each container, allowing for more
efficient mask management. The transportation of the
containers in stacks results in an improvement in
20 efficiency.